

Developing on-machine 3D profile measurement for deterministic fabrication of aspheric mirrors

Richard Pultar

OPTI521

Introduction

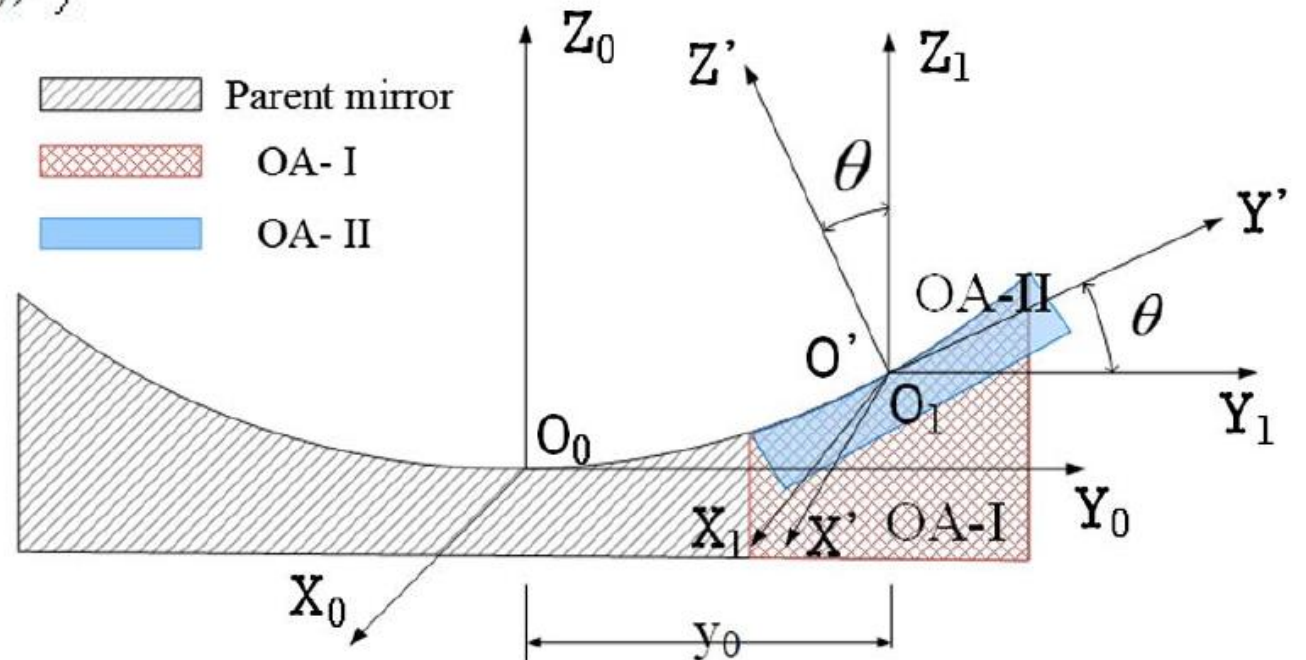
- Aspheric components are a valuable resource for optical design
- Compared to spherical optics, aspheres can reduce size and weight while improving image quality
- Manufacture and metrology of aspheric components is difficult
- Machine tool to measure 3D profile of aspheric mirrors is presented to aid in deterministic manufacturing
- Overview of JR-1800 system
- Sources of error
 - Mechanical errors, alignment errors, temperature, etc.
- Validation Experiments

Aspheric Surfaces

- Parent Mirror:
$$Z(X, Y) = \frac{C(X^2 + Y^2)}{1 + \sqrt{1 - (K+1)C^2(X^2 + Y^2)}} + \sum_{i=1}^n A_{2i}(X^2 + Y^2)^i$$

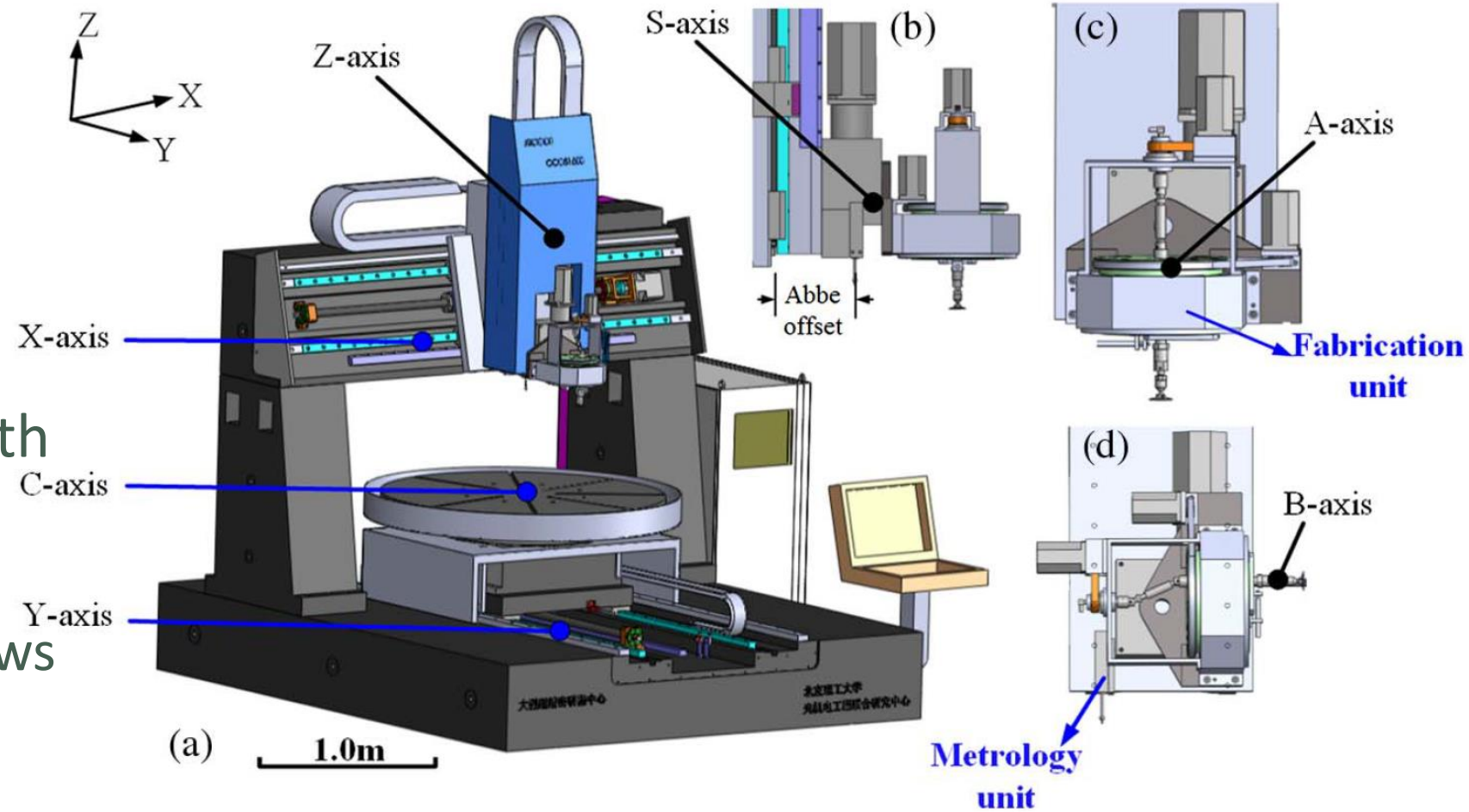
- OA-I:
$$Z_1(X, Y) = \frac{C(X_1^2 + (Y_1 - y_0)^2)}{1 + \sqrt{1 - (K+1)C^2(X_1^2 + (Y_1 - y_0)^2)}} - z_0$$

- OA-II:
$$Z' = \frac{-B + \sqrt{B^2 - 4AQ}}{2A}$$



JR-1800 Measurement System

- Marble Base
- X Travel: 1840 mm
- Y Travel: 2096 mm
- Z Travel: 603 mm
- C Axis: \varnothing 1800 mm
- Heidenhain MT60 length gage
 - Max travel: 60.8 mm
 - Large travel range allows for Z axis to remain stationary eliminating abbe offset error
- XY and XC measurement



Comparison to Interferometry

- Any surface shape can be measured without null correctors or CGHs
- Specular and non-specular surfaces can be measured
- Sag heights are directly measured allowing for analysis of vertex curvature and conic constant
- An accuracy of $\sim 1 \mu\text{m}$ is expected, which is much lower than that of an interferometer.
- Measurement time is dependent on the number of points collected
 - 1000-2000 points per hour

Mechanical Errors

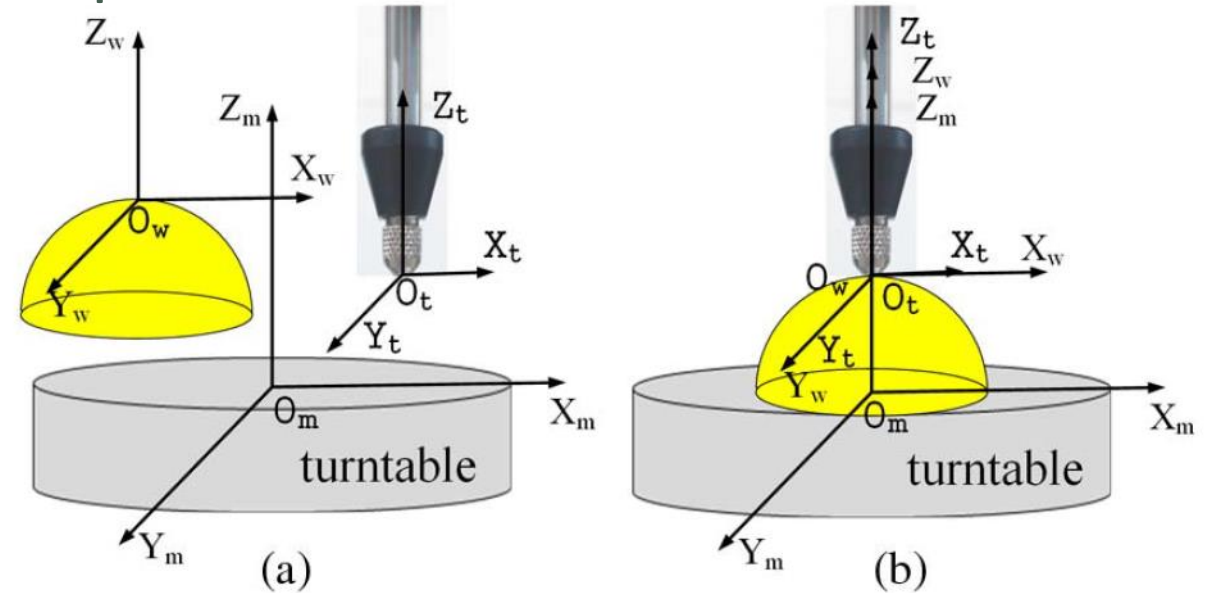
- Linearity of guide rails
 - X axis found to be 1.75 μm
- Positioning error of axes
 - XY positioning errors less than 6.0 μm
 - XY repeatability $\sim 3.3 \mu\text{m}$
 - C positioning errors less than 9.2 s
 - C repeatability $\sim 4.3 \text{ s}$
- C axis radial and axial runout, parallelism of X and C axis, perpendicularity of XY, XZ, and YZ
 - Difficult to correlate with measurement results
- 440 mm x 440 mm reference window with PV = .23 μm was used to calibrate system
 - XC mode PV = 2.3 μm and RMS = 0.38 μm
 - XY mode PV = 3.0 μm and RMS = 0.53 μm
 - Must be subtracted and results are only valid over this area

Table 1. Mechanical Errors of XYZC Axis

Axis	Positioning Accuracy	Repeat Positioning Accuracy	Slider Linearity	Measured Range
X	5.9 μm	3.3 μm	1.75 μm	1600 mm
Y	5.6 μm	3.2 μm	4.30 μm	2000 mm
Z	2.2 μm	1.3 μm	1.66 μm	600 mm
C	9.2 s	4.3 s	—	360°

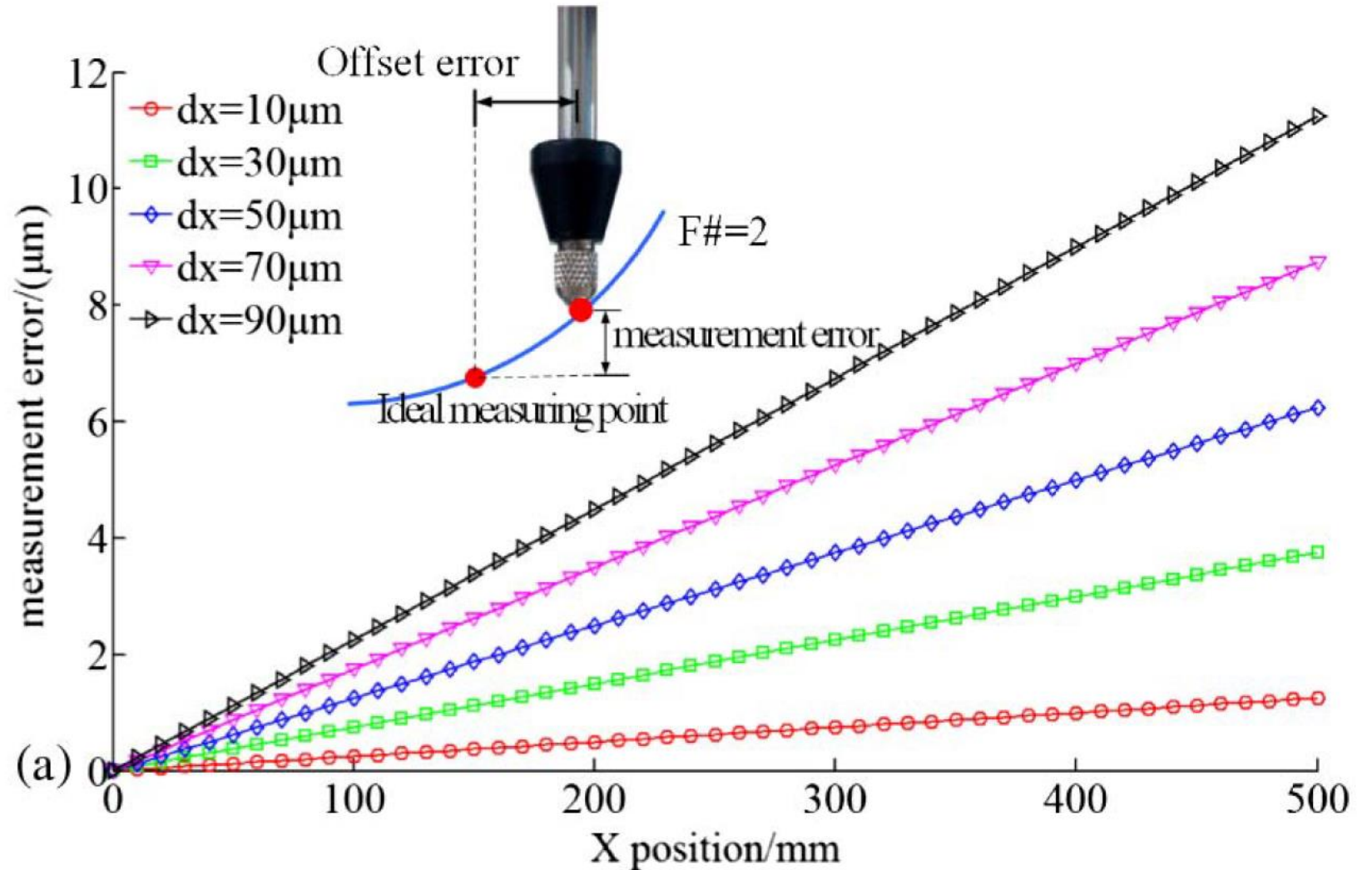
Length Gage Alignment

- Length gage must be aligned to the workpiece
- Three coordinates of interest
 - Center of the turntable
 - Vertex of the workpiece
 - Vertex of the probe tip
- Alignment process:
 - Center calibration sphere to turntable with dial indicator until there is less than 0.001 mm of runout
 - Profile in X and Y direction
 - Using these profiles reposition probe tip
- $\pm 5 \mu\text{m}$ offset was achievable



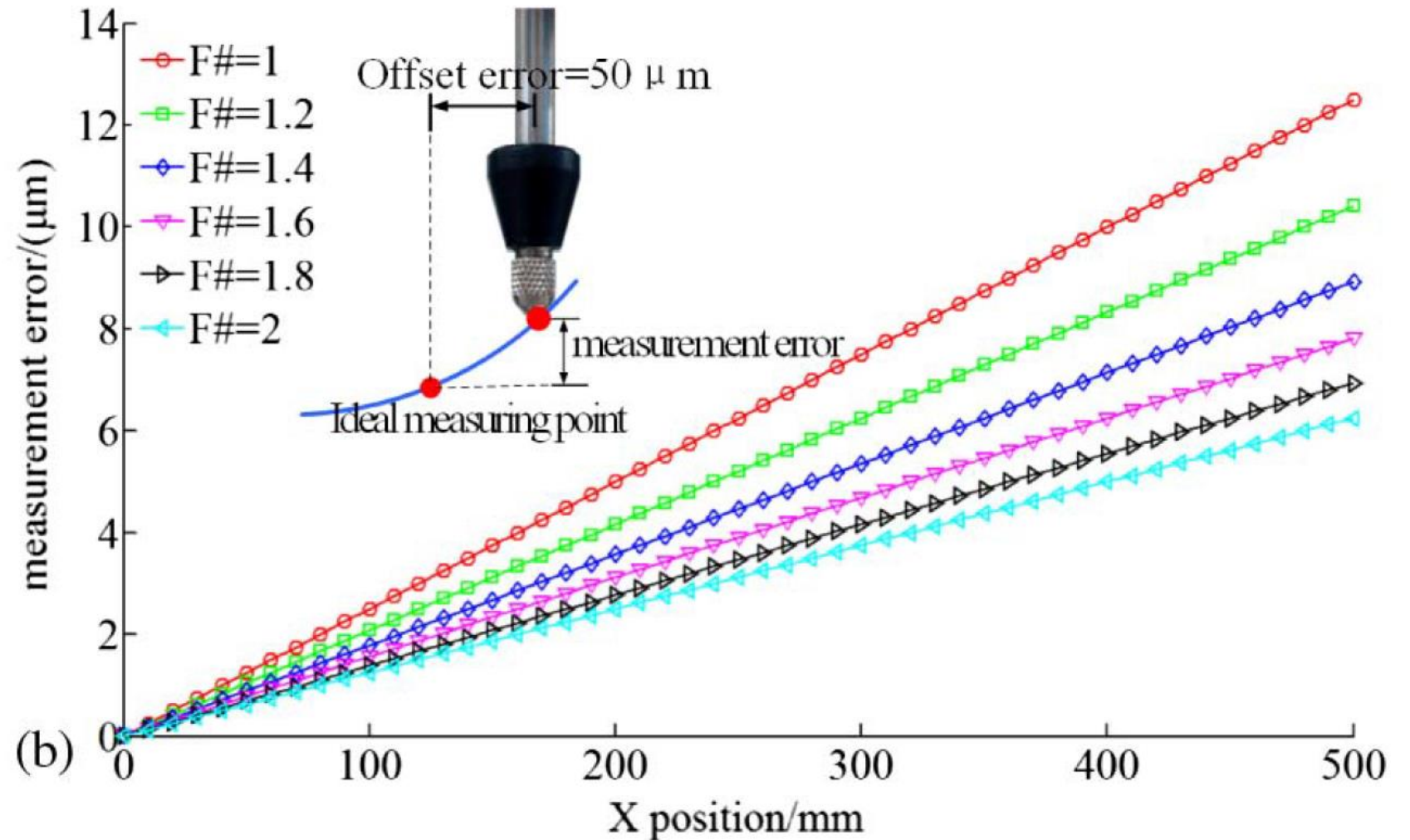
Length Gage Alignment

- Misalignment in X produces a linear error proportional to $F/\#$



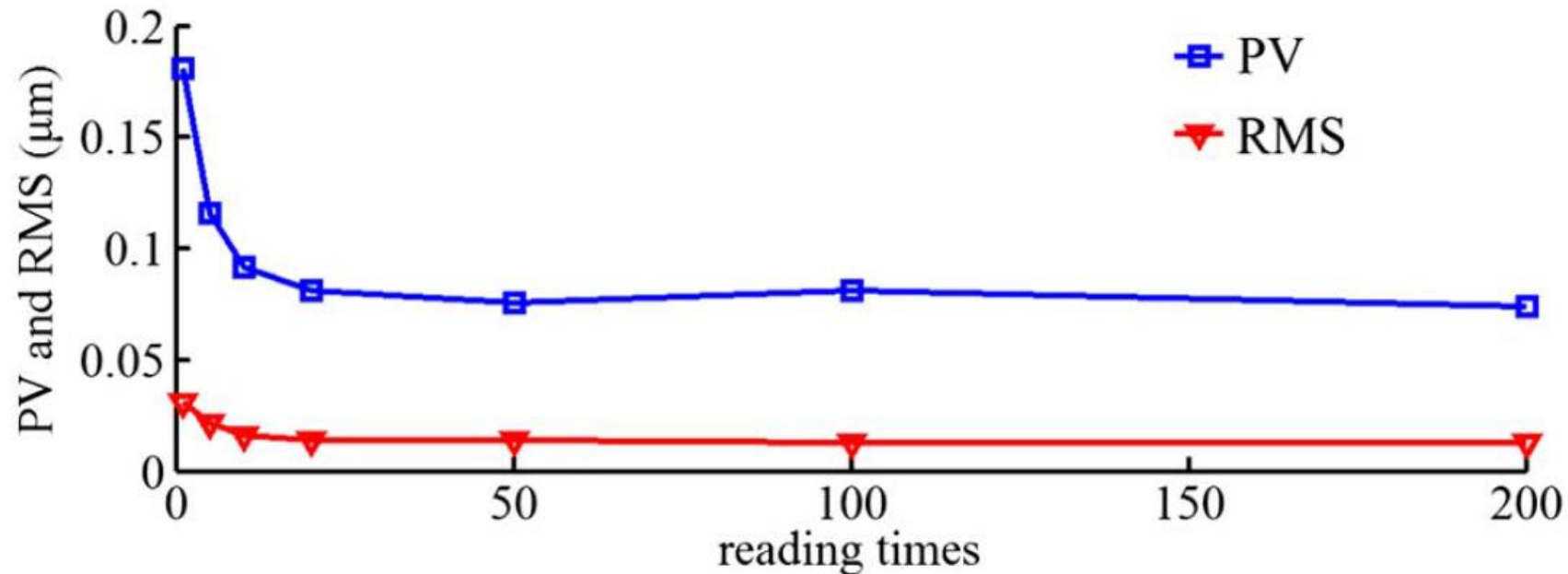
Length Gage Alignment

- Misalignment in X produces a linear error proportional to F/#



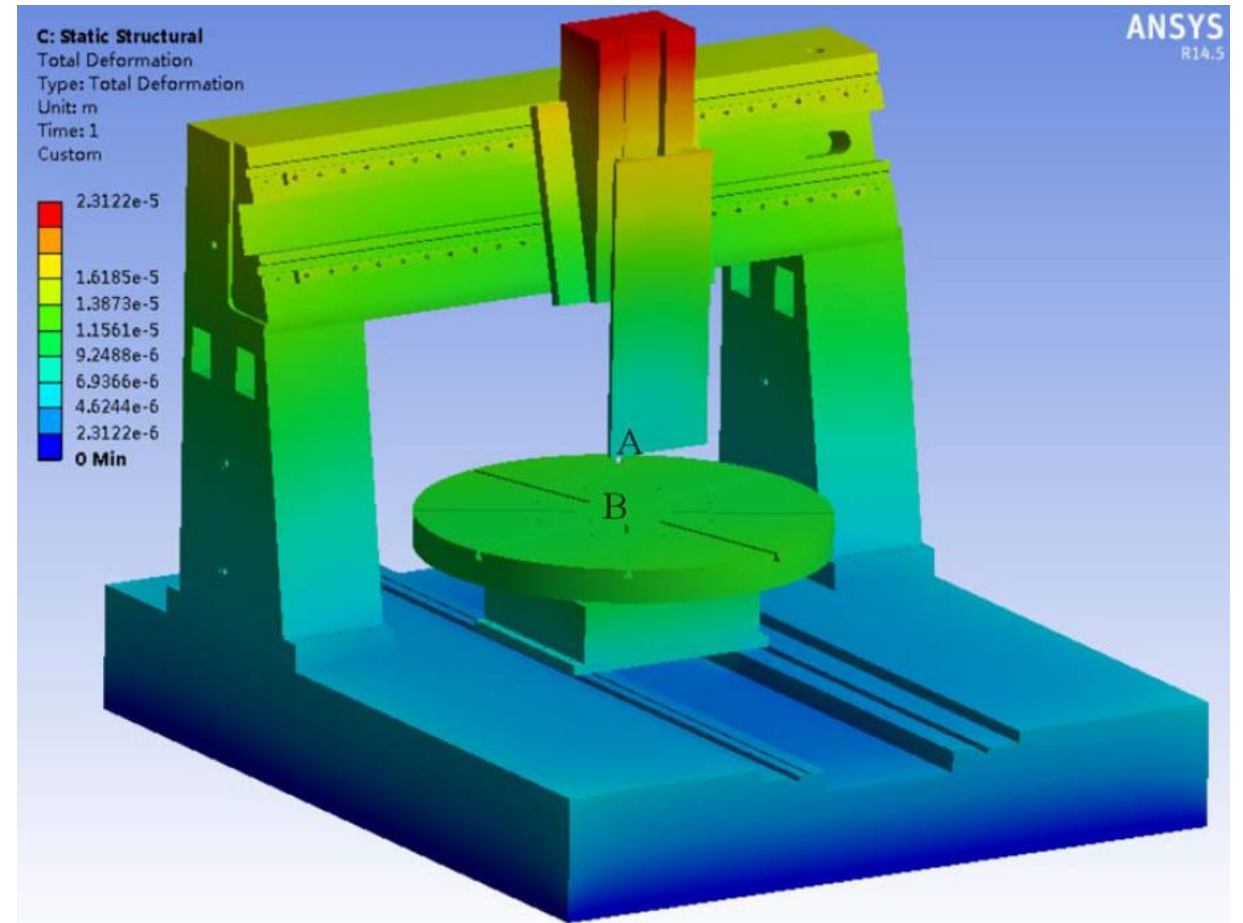
Length Gage Stability

- Measurement can vary $0.02 - 0.05 \mu\text{m}$ while in contact with the surface



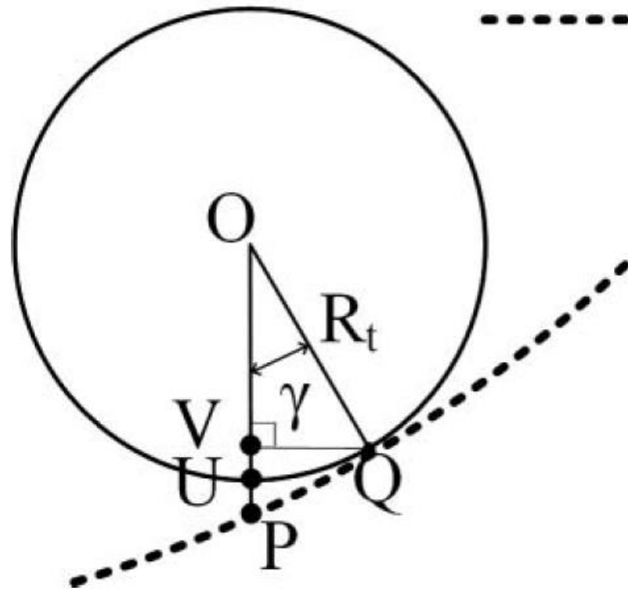
Influence of Temperature

- Maximum deformation of 23 μm with an increase of 1°C
- Only $0.91 \mu\text{m}/^\circ\text{C}$ at points A and B
- System is maintained to $20 \pm 0.2^\circ\text{C}$ resulting in $\pm 0.182 \mu\text{m}$
- MT60 deforms $0.16 \mu\text{m}/^\circ\text{C}$ resulting in $\pm 0.032 \mu\text{m}$
- Workpiece also need to be considered



Tool Radius Compensation

- The spherical probe tip will induce a nonlinear error into the measurement
- The theoretical sagittal deviations of points U and P are added to correct this error

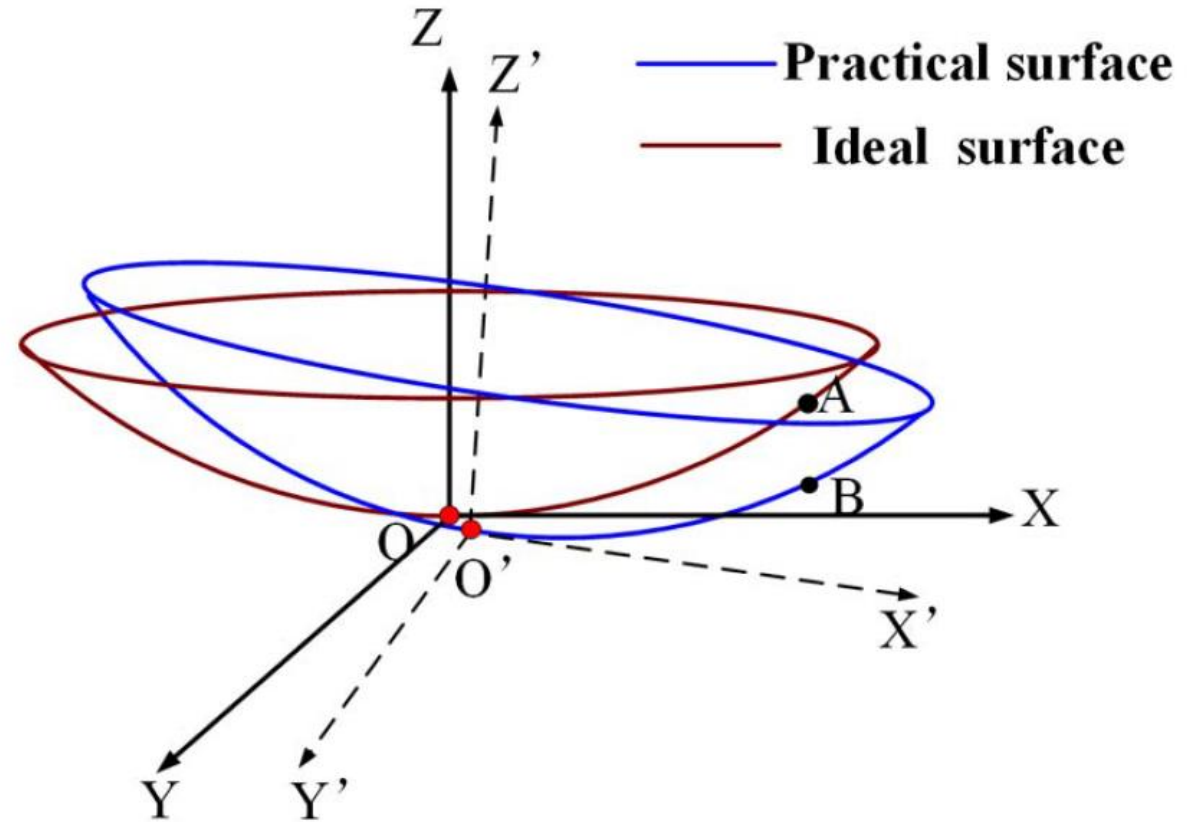


----- Curved surface
O: Sphere center
U: the lowest point of sphere
Q: the factual contact point
P: the point to be measured

$$Z_{UP} = Z\left(\sqrt{X_P^2 + Y_P^2} + R_t \sin(\gamma), 0\right) - Z\left(\sqrt{X_P^2 + Y_P^2}, 0\right) - R_t(1 - \cos(\gamma))$$

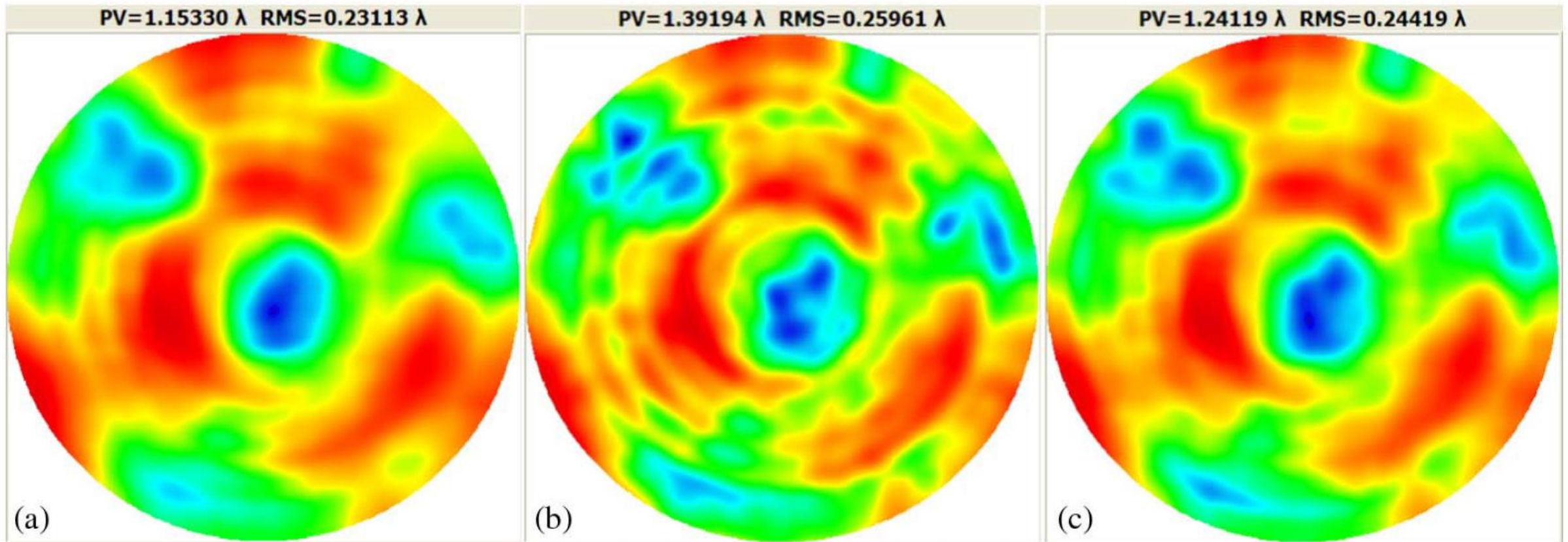
Tilt and Offset Compensation

- Residual error due to misalignment still remains
- Least-squares algorithm is then used to fit the measured points to compute final surface form



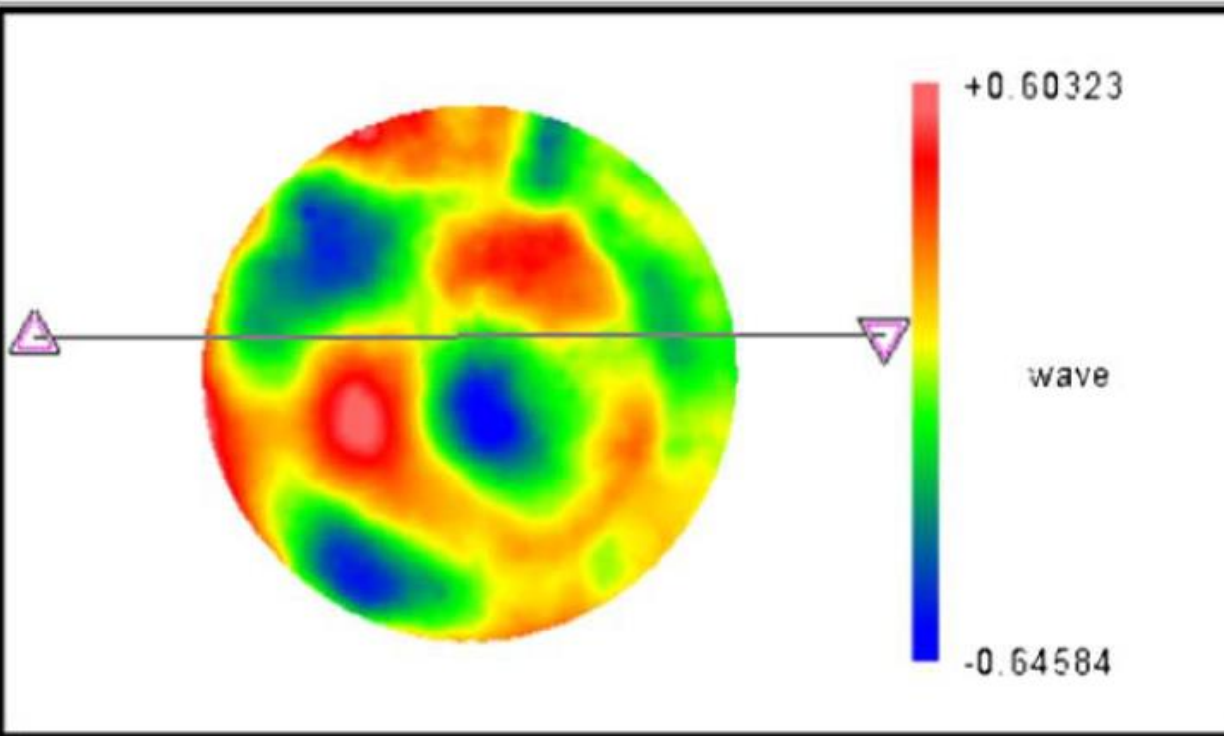
Validation Experiments

- Concentric circle path was chosen with points spaced every 8 mm on $\varnothing 400$ mm window
- RMS deviation less than $1/30 \lambda$



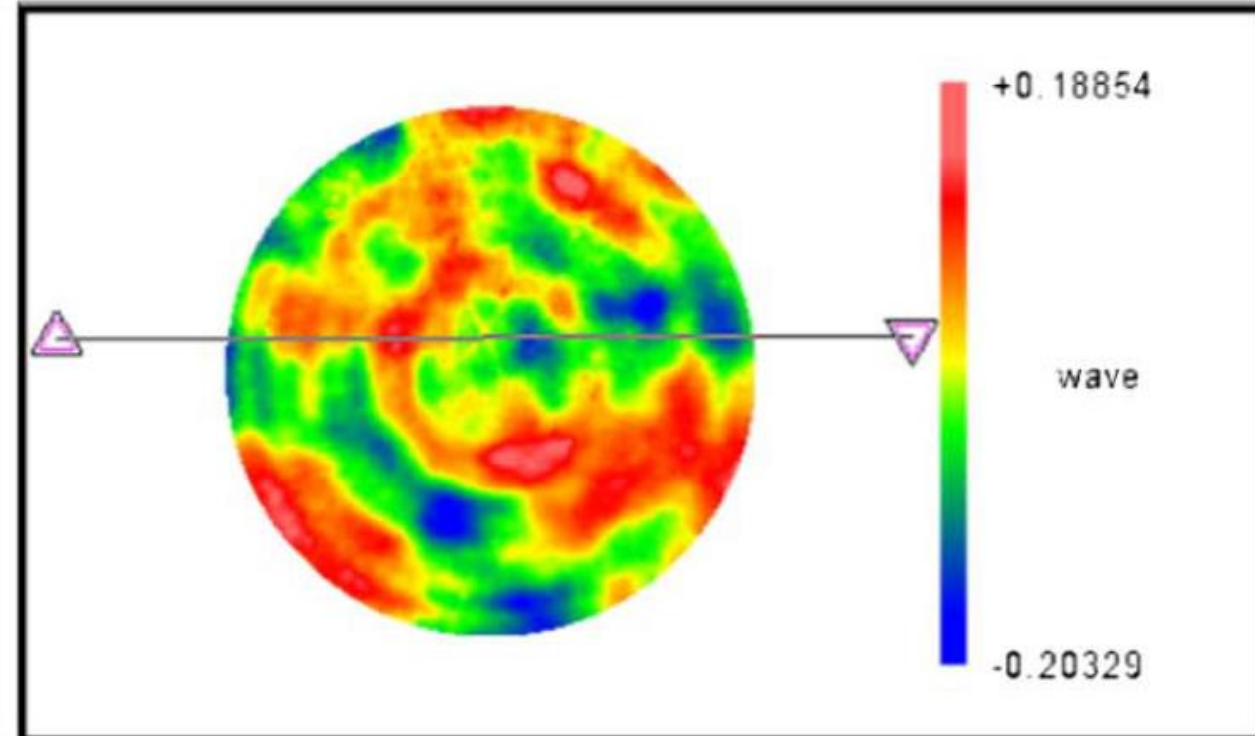
Validation Experiments

- Direct subtraction of measurement results from Zygo GPI and JR-1800



PV	1.249	wave
rms	0.231	wave
Power	0.060	wave

(a)



PV	247.950	nm
rms	42.314	nm
Power	-0.066	wave

(b)

Validation Results

- Measurement of parabolic surface $\varnothing 320$ mm, $R = 4000$ mm
- Measurement error PV = $0.512 \mu\text{m}$, RMS = $0.067 \mu\text{m}$

